

## MOSFETs

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## Introduction

- Transistors are **three-terminal** devices —unlike diodes, which have only two
- The basic usage of a transistor is the ability to use the voltage between two terminals to control the current flowing in the third terminal
- They are more useful because they present multitude of applications: signal amplification, digital logic, memory, etc. . .
- There are two major types of three-terminal semiconductor devices:
  - **BJT**—bipolar junction transistor
  - **MOSFET**—metal oxide-semiconductor field-effect transistor
- MOSFETs are considered preferable to BJT technology for many applications and are much widely used because:
  - size (smaller)
  - ease of manufacture
  - lesser power utilization

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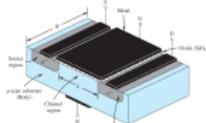
MOSFETs

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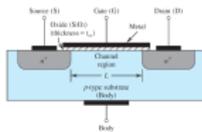
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## MOSFET structure

- two n-type doped regions (drain, source), and one p-type doped region
- layer of  $\text{SiO}_2$  separates source and drain
- metal, placed on top of  $\text{SiO}_2$ , forms gate electrode
- Four terminals: the gate(G), the source (S), the drain (D) and the Body (B).



(a) perspective view



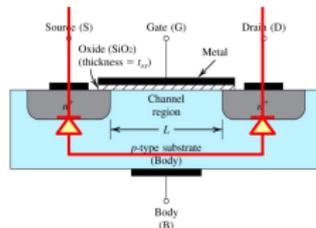
(b) cross section

**FIG 1. Physical structure of the enhancement-type NMOS transistor.**

Typically  $L = 0.03 \mu\text{m}$  to  $1 \mu\text{m}$ ,  $W = 0.05 \mu\text{m}$  to  $100 \mu\text{m}$ , and the thickness of the oxide layer ( $t_{ox}$ ) is in the range of 1 to 10 nm.

## Operations with zero gate voltage

- With zero voltage applied to gate, **two back-to-back diodes** exist in series between drain and source.
- These diodes prevent current conduction from drain to source when a voltage  $v_{DS}$  is applied.
- In short, the path between drain and source has a very high resistance (of the order of  $10 \text{ T}\Omega$ ).



## Creating a channel for current flow

What would happen if (1) the source and drain are grounded and (2) a positive voltage is applied to gate ?

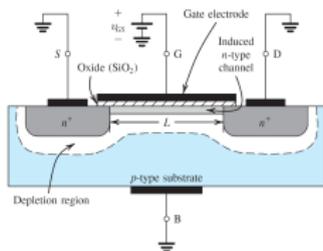


FIG 2. The enhancement-type NMOS transistor with a positive voltage applied to the gate. An n-channel is induced at the top of the substrate beneath the gate.

## Creating a channel for current flow

- **Step 1**— $V_{GS}$  is applied to the gate terminal, causing a positive build up of positive charge along metal electrode.
- **Step 2**—This “build up” causes **free holes to be repelled** from region of p-type substrate under gate.

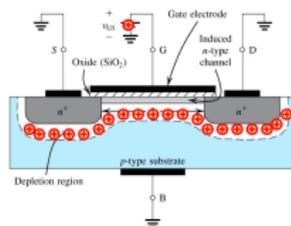


FIG 3. The enhancement-type NMOS transistor with a positive voltage applied to the gate. An n-channel is induced at the top of the substrate beneath the gate.

## Creating a channel for current flow

- **Step 1**— $V_{GS}$  is applied to the gate terminal, causing a positive build up of positive charge along metal electrode.
- **Step 2**—This “build up” causes **free holes to be repelled** from region of p-type substrate under gate.
- **Step 3**—This “migration” results in the uncovering of negative **bound charges**, originally neutralized by the free holes
- **Step 4**—The positive gate

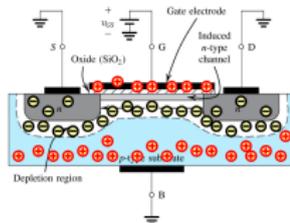


FIG 4. The enhancement-type NMOS transistor with a positive voltage applied to the gate. An n-channel is induced at the top of the substrate beneath the gate.

## Creating a channel for current flow

- **Step 5**—Once a sufficient number of these electrons accumulate, an n-region is created and connects the source and drain regions
- **Step 6**—This provides path for current flow between D and S.
- **Note:** This induced channel is also known as an **inversion layer**

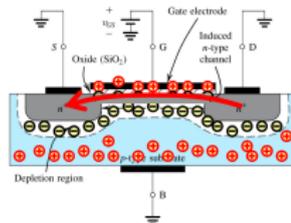


FIG 5. The enhancement-type NMOS transistor with a positive voltage applied to the gate. An n-channel is induced at the top of the substrate beneath the gate.

## Creating a channel for current flow

- **threshold voltage**  $V_t^1$  – is the minimum value of  $v_{GS}$  required to form a conducting channel between drain and source and is between 0.3 and 0.6V<sup>2</sup>
- **field-effect** —when positive  $v_{GS}$  is applied, an electric field develops between the gate electrode and induced n-channel – the conductivity of this channel is affected by the strength of field. The  $SiO_2$  layer acts as dielectric
- The difference between  $v_{GS}$  applied and  $V_t$  is termed the **effective voltage** or the **overdrive voltage** and is the quantity that determines the charge in the channel. It is noted as shown in **Equation** (1)

$$v_{GS} - V_t \equiv v_{OV} \quad (1)$$

<sup>1</sup>do not confuse  $V_t$  with  $V_T$ —The latter is used to denote the thermal voltage  $VT$

<sup>2</sup> $V_{tn}$  is used for n-type MOSFET and  $V_{tp}$  is used for p-channel

## Creating a channel for current flow

- Since the parallel plate capacitor is given by expressed by the area  $A$  and the distance  $d$  between the plates **Equation** (5)

$$C = \frac{\epsilon A}{d} \quad (5)$$

- Then, the **oxide capacitance** ( $C_{ox}$ ) (i.e., the capacitance of the parallel plate capacitor per unit gate area ( $F/m^2$ )) is given by

$$C_{ox} = \epsilon_{ox}/t_{ox} \quad (6)$$

where:

$\epsilon_{ox}$  is the permittivity of the silicon dioxide

$$\epsilon_{ox} = 3.45 \times 10^{-11} F/m$$

$t_{ox}$  is the thickness of the silicon layer  $SiO_2$

- The voltage across the silicon layer must exceed  $V_t$  for the n-channel to form
- As  $v_{OV}$  grows, so does the depth of the n-channel as well as

## Creating a channel for current flow

- A conducting channel forms a parallel plate capacitor with the gate
- The charge  $Q$  created in the channel is given by **Equation** (2) and **Equation** (3)

$$Q = CV \quad (2)$$

$$|Q| = C_g \cdot v_{OV} \quad (3)$$

Where the gate capacitor is given by **Equation** (4)

$$C_g = C_{ox} WL \quad (4)$$

Where:

$C_{ox}$  is the capacitance per unit area  
 $WL$  is the area of the electrode

## Small $v_{DS}$ Model

## Small $v_{DS}$ Model for MOSFET

What is the current  $i_D$  For small values of  $v_{DS}$  (i.e., 50 mV or so)?

- The charge of the parallel plate capacitor between the gate and the channel is given by Equation (8)

$$Q = CV \quad (7)$$

$$|Q| = C_{ox}WLv_{OV} \quad (8)$$

- The charge per unit length  $Q_n$  is then given by Equation (9)

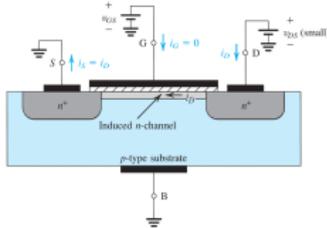


FIG 6. An NMOS transistor with  $v > V_t$  and with a small  $v_{DS}$  applied. The device acts as a resistance whose value is determined by  $v_{GS}$ . Specifically, the channel conductance is proportional to  $v_{GS} - V_t$ , and thus  $i_D$  is proportional to  $(v_{GS} - V_t)v_{DS}$ .

## Small $v_{DS}$ Model for MOSFET

- Then the electric field along the channel is given by Equation (10)

$$|E| = \frac{v_{DS}}{L} \quad (10)$$

- The drift velocity of the electrons is given by Equation (11)

$$\begin{aligned} v_{drift} &= \mu_n |E| \\ &= \mu_n \frac{v_{DS}}{L} \end{aligned} \quad (11)$$

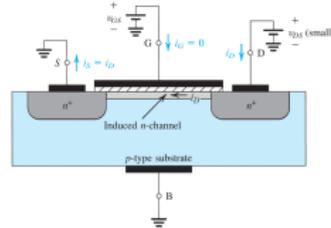


FIG 7. An NMOS transistor with  $v > V_t$  and with a small  $v_{DS}$  applied. The device acts as a resistance whose value is determined by  $v_{GS}$ . Specifically, the channel conductance is proportional to  $v_{GS} - V_t$ , and thus  $i_D$  is proportional to  $(v_{GS} - V_t)v_{DS}$ .

## Small $v_{DS}$ Model for MOSFET

- For small  $v_{DS}$ , we can assume that the voltage between the gate and various points along the channel is equal to  $v_{GS}$ .  $i_D$  is given by Equation (12)<sup>2</sup>

$$\begin{aligned} i_D &= Q_n v_{drift} \\ &= C_{ox} W v_{OV} \mu_n \frac{v_{DS}}{L} \\ &= \left[ \mu_n C_{ox} \left( \frac{W}{L} \right) v_{OV} \right] v_{DS} \\ &= \left[ \mu_n C_{ox} \left( \frac{W}{L} \right) (v_{GS} - V_t) \right] v_{DS} \end{aligned} \quad (12)$$

- The conductance is given by Equation (13)

$$\begin{aligned} g_{DS} &= \mu_n C_{ox} \left( \frac{W}{L} \right) v_{OV} \\ &= \mu_n C_{ox} \left( \frac{W}{L} \right) (v_{GS} - V_t) \end{aligned} \quad (13)$$

## Small $v_{DS}$ Model for MOSFET

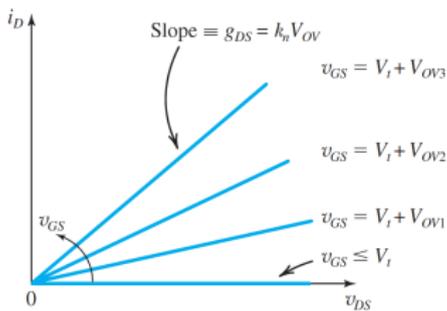
- The factor  $k'_n = \mu_n C_{ox}$  is called the **process transconductance** and is affected by the type of manufacturing process
- The ratio of the width  $W$  to the length  $L$  (i.e.,  $W/L$ ) affects the conductance. For example, in the recent 5nm lithography technology process, the channel length  $L$  cannot be smaller than 5nm.
- A **MOSFET transconductance parameter** is given by

$$k_n = k'_n \frac{W}{L} = \mu_n C_{ox} \frac{W}{L} \quad (14)$$

- The conductance depends on  $v_{GS}$

$$\begin{aligned} r_{DS} &= 1/g_{DS} \\ &= 1/\left[ \mu_n C_{ox} \left( \frac{W}{L} \right) v_{OV} \right] \\ &= \frac{1}{\mu_n C_{ox} \left( \frac{W}{L} \right) (v_{GS} - V_t)} \end{aligned} \quad (15)$$

<sup>2</sup>See details in the textbook on page 253

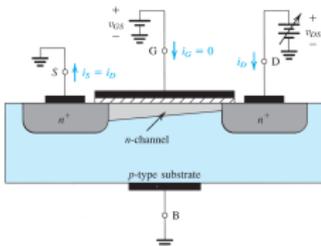


**FIG 8. MOSFET operations for various values of  $v_{GS}$**   
 A MOSFET is a voltage-controlled resistance. The slope of the curve which is  $g_{DS}$  is dependent on  $v_{GS}$  since  $V_{OV} = v_{GS} - V_t$ . When the voltage applied between drain and source,  $v_{DS}$ , is kept small, the device operates as a linear resistance whose value is controlled by  $v_{GS}$ .

## Large $v_{DS}$ Model

## Large $v_{DS}$ Model of a MOSFET

- Let's assume  $v_{OV}$  is constant. In this case, as  $v_{DS}$  increases, the induced channel width will be different.
- Different  $v_{GS}$  will draw different amount of n carrier into the channel creating a non-uniform depth of the channel as shown in Fig. 9
- The channel depth is proportional to  $v_{GS}$  at the source end or

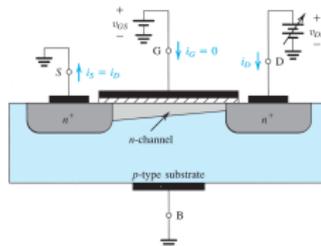


**FIG 9. Operation of an NMOS transistor as  $v_{DS}$  is increased.** Note that an unequal channel depth is induced when a larger  $v_{DS}$  is applied across the transistor giving rise to non-uniform channel depth

## Large $v_{DS}$ Model of a MOSFET

- The channel depth is proportional to  $v_{GD}$  at the drain end or

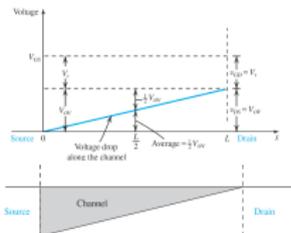
$$v_{GD} = V_t + V_{OV} - v_{DS} \quad (17)$$



**FIG 10. Operation of an NMOS transistor as  $v_{DS}$  is increased.** Note that an unequal channel depth is induced when a larger  $v_{DS}$  is applied across the transistor giving rise to non-uniform channel depth



# Channel Pinch-Off and Current Saturation



**FIG 13. Operation of MOSFET with  $v_{GS} = V_T + V_{OV}$**   
 When  $v_{DS} = V_{OV}$ , at the drain end,  $v_{GD}$  decreases to  $V_T$  and the channel depth at the drain end reduces to zero (pinch-off). At this point, the MOSFET enters the saturation mode of operation. Further increasing  $v_{DS}$  has no effect on the channel shape and  $i_D$  remains constant.

# Channel Pinch-Off and Current Saturation

- When  $v_{DS} = V_{OV}$ , then the channel depth is zero near the drain end
- At this junction, increasing  $v_{DS}$  does not increase the drain current  $i_D$

$$i_{Dsat} = \frac{1}{2} k' \frac{W}{L} V_{OV}^2 \quad (21)$$

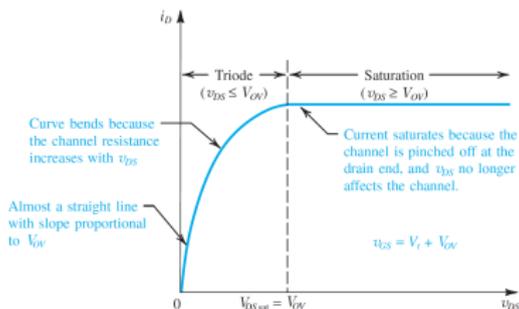
- The saturation voltage is given by

$$V_{DSsat} = V_{OV} = V_{GS} - V_T \quad (22)$$

- In general, as a function of  $v_{OV}$ , in the saturation region,

$$\begin{aligned} i_D &= \frac{1}{2} k'_n \frac{W}{L} v_{OV}^2 \\ &= \frac{1}{2} k'_n \frac{W}{L} (v_{GS} - V_T)^2 \end{aligned} \quad (23)$$

- In the saturation region, the relation between  $i_{DS}$  and  $v_{GS}$  is nonlinear.

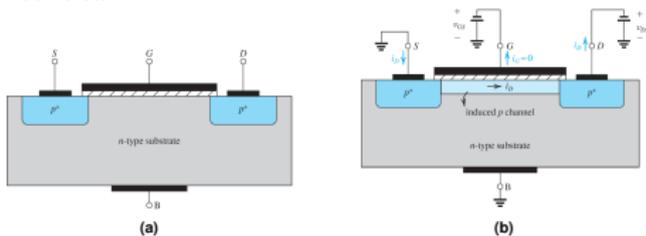


**FIG 14. The drain current  $i_D$  versus the drain-to-source voltage  $v_{DS}$  for an NMOS transistor operated with  $v_{GS} = V_T + V_{OV}$**

# The p and Complementary MOSFET

# The p-Channel MOSFET

A PMOS can be made by replacing p region with n region and vice versa



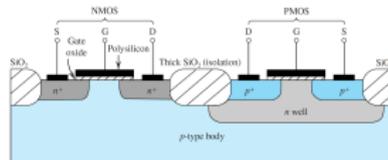
**FIG 15. Physical structure of the PMOS transistor**

Note that it is similar to the NMOS transistor except that all semiconductor regions are reversed in polarity. Fig. 15b shows the effect of a negative voltage  $v_{GS}$  of magnitude greater than  $V_{tp}$ . This negative voltage induces a p-channel, and a negative  $v_{DS}$  causes a current  $i_D$  to flow from source

# The complementary MOS of CMOS

CMOS employs MOS transistors of **both polarities**.

- more difficult to fabricate
- more powerful and flexible
- now more prevalent than NMOS or PMOS



**FIG 16. Cross section of a CMOS integrated circuit.**

Note that the PMOS transistor is formed in a separate n-type region, known as an n well. Another arrangement is also possible in which an n-type substrate (body) is used and the n device is formed in a p well. Not shown are the connections made to the p-type body and to the n well; the latter functions as the body terminal for the p-channel device.

End